

Resource Summary Report

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YXLON: FF70 CL X-Ray System

RRID:SCR_020908

Type: Tool

Proper Citation

YXLON: FF70 CL X-Ray System (RRID:SCR_020908)

Resource Information

URL: <https://www.yxlon.com/en/products/x-ray-and-ct-inspection-systems/yxlon-ff70-cl>

Proper Citation: YXLON: FF70 CL X-Ray System (RRID:SCR_020908)

Description: X ray inspection system has been developed to enable automated analysis for flaws in semi-conductors. Flaws can be found on wafer, on substrate, in strip in sub assembly or in final device.

Resource Type: instrument resource

Keywords: YXLON, X-Ray System, Instrument Equipment, USEDit,

Availability: Commercially available

Resource Name: YXLON: FF70 CL X-Ray System

Resource ID: SCR_020908

Alternate IDs: Model_Number_FF70

Record Creation Time: 20220129T080352+0000

Record Last Update: 20260912T195948+0000

Ratings and Alerts

No rating or validation information has been found for YXLON: FF70 CL X-Ray System.

No alerts have been found for YXLON: FF70 CL X-Ray System.

Data and Source Information

Source: [SciCrunch Registry](#)

Usage and Citation Metrics

We have not found any literature mentions for this resource.